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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Gopinath et al.

Attorney Docket No.: NOVLP030/NVLS-000497

Application No.: 10/016,017

Examiner: Not yet assigned

Filed: December 12, 2001

Group: 2812

Title: METHOD AND APPARATUS FOR INTRODUCTION OF SOLID PRECURSORS AND REACTANTS INTO A SUPERCRITICAL

FLUID REACTOR

CERTIFICATE OF MAILING

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INFORMATION DISCLOSURE STATEMENT 37 CFR §§1.56 AND 1.97(b)

Signed

Commissioner for Patents Washington, DC 20231

Dear Sir:

The references listed in the attached PTO Form 1449, copies of which are attached, may be material to examination of the above-identified patent application. Applicants submit these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure

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dement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NVLSP030).

Respectfully submitted,

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n 1449 (Modified)

Atty Docket No. NOVLP030/NVLS-000497 Application No.: 10/016,017

Information Disclosure Statement By Applicant Applicant: Gopinath et al. Filing Date

Group

2812

(Use Several Sheets if Necessary)

December 12, 2001

U.S. Patent Documents

Examiner						Sub-	Filing
Initial	No.	Patent No.	Date	Patentee	Class	class	Date
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Foreign Patent or Published Foreign Patent Application

Examiner		Document	Publication			Sub-	Trans	lation
Initial	No.	No.	Date	Patent Office	Class	class	Yes	No

Other Documents

Examiner						
Initial	No.					
	Α	Costantini et al., "Supercritical Fluid Delivery and Recovery System for				
		Semiconductor Wafer Processing", Pub. No.: US 2001/0050096 A1, Pub.				
	ļ	Date: Dec. 13, 2001, Appl. No.: 09/837,507, Filed: April 18, 2001, pages 1-15				
	В	Chandra et al., "Supercritical Fluid Cleaning Process for Precision Surfaces",				
		Pub. No.: US 2002/0014257 A1, Pub Date: Feb. 7, 2002, Appl. No.				
		09/861,298, Filed: May 18, 2001, pages 1-21.				
Examiner		Date Considered				
<u> </u>						

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.